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CONFIRMATION NO. 8166

SERIAL NUMBER	FILING or 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.		
10/587,427	07/26/2006	438	1792	Serie 6497		
RULE						
APPLICANTS Eri Tsukada, Ibaraki, JAPAN; Christian Dussarrat, Ibaraki, JAPAN; Jean-Marc Girard, Paris, FRANCE; ** CONTINUING DATA ***** This application is a 371 of PCT/IB05/00170 01/19/2005 ** FOREIGN APPLICATIONS ***** JAPAN 2004-025479 02/02/2004 ** IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 04/04/2007						
Foreign Priority claimed <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No 35 USC 119(a-d) conditions met <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No Verified and /BRET P CHEN/ Acknowledged Examiner's Signature		<input type="checkbox"/> Met after Allowance Initials	STATE OR COUNTRY JAPAN	SHEETS DRAWINGS 1	TOTAL CLAIMS 10	INDEPENDENT CLAIMS 2
ADDRESS AIR LIQUIDE Intellectual Property 2700 POST OAK BOULEVARD, SUITE 1800 HOUSTON, TX 77056 UNITED STATES						
TITLE Method for producing silicon nitride films and silicon oxynitride films by chemical vapor deposition						
FILING FEE RECEIVED 900	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:			<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit		